



## FOR DISCUSSION PURPOSES ONLY

	Control Hardware - Qty (1)	
	Control Software - Qty (1)	
	Other	
	<b>FAAMS 600C-1 PVD system</b>	
	CAD sources, DCAD-250C, - Qty (2)	
	2 rotary magnetrons, SCI, 3"dia, movable shield, height, 400 mm	
	Plasma duct chamber height 500 mm	
	Coating chamber height 600, mm	
	Filter's magnetic coils, Qty (6 ea.)	
	TMP Ebara EBT1400 1,400 l/s for ISO200 flange	
	Dry mechanical pump Leibold LV1400	
	Primary arc power supply, Miller Phoenix 456 CC/CV DC inverter (2 ea.)	
	Remote arc power supplies, Miller Phoenix 456 CC/CV DC inverter (4 ea.)	
	DCAD-250C steering&focusing coils power supply, Agilent E3649A 100W Dual (2 ea.)	
	DCAD-250C rastering coils power supply, (2ea.)	
	Power supplies for filter's coils, Thermal Arc 160 S INVERTER ARC WELDER, Qty (3 ea.)	
	Rotary magnetron power supply, AEI Pinnacle Plus (2 ea.)	
	Substrate Bias Power Supply, AEI Solvix DC Plus Bias, 300 kHz	
	Rotary table	
	Control hardware	
	Control software	
	Other	
	<b>FAAMS 1000C-1 PVD system</b>	
	CAD sources, DCAD-250C, - Qty (4)	
	2 rotary magnetrons, SCI, 3"dia, movable shield, height, 800 mm	
	Plasma duct chamber height 900 mm	
	Coating chamber height 1000, mm	
	Filter's magnetic coils, Qty (6)	
	TMP Ebara EBT2400 2,400 l/s for ISO250 flange	
	Dry mechanical pump Leibold LV1400	
	Primary arc power supply, Miller Phoenix 456 CC/CV DC inverter (4 ea.)	

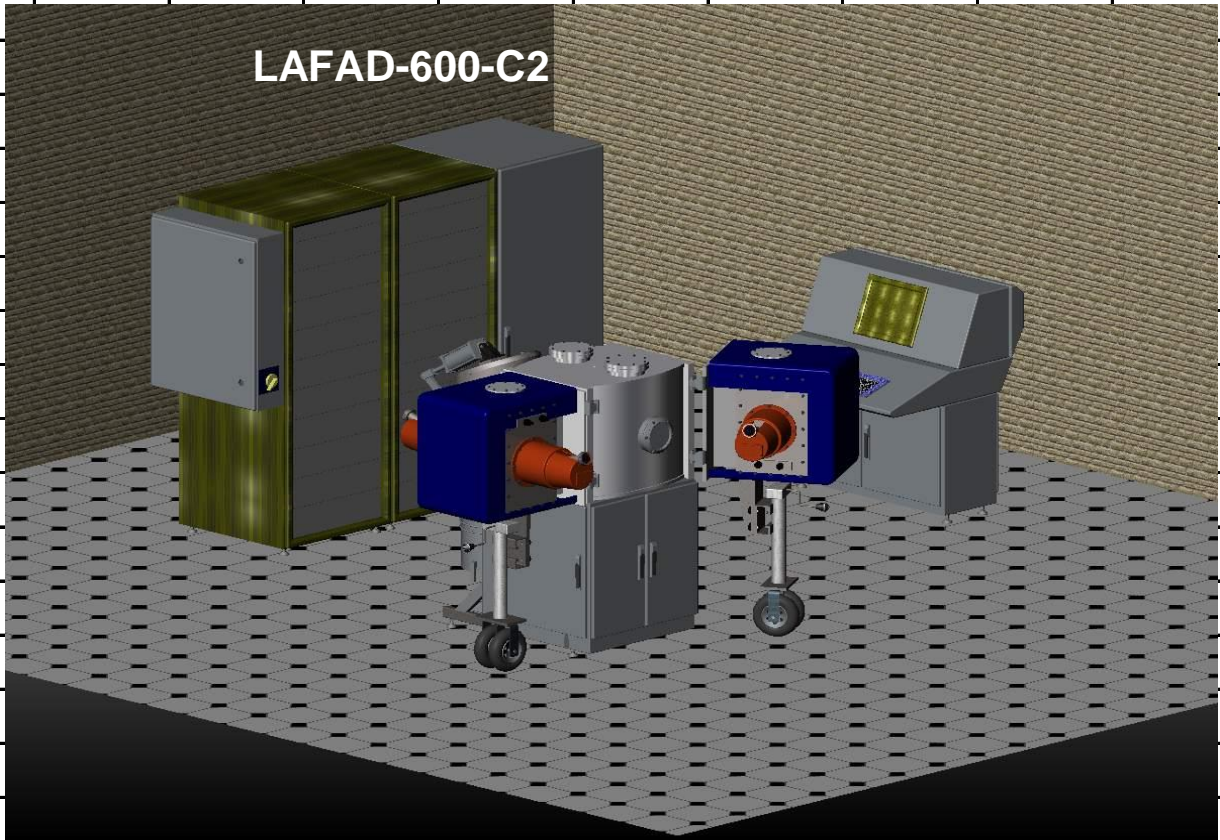
## FOR DISCUSSION PURPOSES ONLY

	Remote arc power supplies, Miller Phoenix 456 CC/CV DC inverter (4 ea.)	
	DCAD-250C steering&focusing coils power supply, Agilent E3649A 100W Dual (4ea.)	
	DCAD-250C rastering coils power supply, (4ea.)	
	Power supplies for filter's coils, Thermal Arc 160 S INVERTER ARC WELDER, Qty (3)	
	Rotary magnetron power supply, AEI Pinnacle Plus (2 ea.)	
	Substrate Bias Power Supply, AEI Solvix DC Plus Bias, 300 kHz	
	Rotary table	
	Control hardware	
	Control software	
	Other	
	<b>FAAMS 600C-2 PVD system</b>	
	CAD sources, DCAD-250C, - Qty (2)	
	4 rotary magnetrons, SCI, 3" dia, movable shield, height, 400 mm	
	Plasma duct chamber height 500 mm	
	Coating chamber height 600, mm	
	Filter's magnetic coils, Qty (12 ea.)	
	TMP Ebara EBT1400 1,400 l/s for ISO200 flange	
	Dry mechanical pump Leibold LV1400	
	Primary arc power supply, Miller Phoenix 456 CC/CV DC inverter (4 ea.)	
	Remote arc power supplies, Miller Phoenix 456 CC/CV DC inverter (8 ea.)	
	DCAD-250C steering&focusing coils power supply, Agilent E3649A 100W Dual (4 ea.)	
	DCAD-250C rastering coils power supply, (4ea.)	
	Power supplies for filter's coils, Thermal Arc 160 S INVERTER ARC WELDER, Qty (6 ea.)	
	Rotary magnetron power supply, AEI Pinnacle Plus (4 ea.)	
	Substrate Bias Power Supply, AEI Solvix DC Plus Bias, 300 kHz	
	Rotary table	
	Control hardware	
	Control software	
	Other	

## FOR DISCUSSION PURPOSES ONLY

	<b>FAAMS 1000C-2 PVD system</b>	
	CAD sources, DCAD-250C, - Qty (8)	
	4 rotary magnetrons, SCI, 3"dia, movable shield, height, 800 mm	
	Plasma duct chamber height 900 mm	
	Coating chamber height 1000, mm	
	Filter's magnetic coils, Qty (12)	
	TMP Ebara EBT2400 2,400 l/s for ISO250 flange	
	Dry mechanical pump Leibold LV1400	
	Primary arc power supply, Miller Phoenix 456 CC/CV DC inverter (8 ea.)	
	Remote arc power supplies, Miller Phoenix 456 CC/CV DC inverter (8 ea.)	
	DCAD-250C steering&focusing coils power supply, Agilent E3649A 100W Dual (8ea.)	
	DCAD-250C rastering coils power supply, (8ea.)	
	Power supplies for filter's coils, Thermal Arc 160 S INVERTER ARC WELDER, Qty (6)	
	Rotary magnetron power supply, AEI Pinnacle Plus (4 ea.)	
	Substrate Bias Power Supply, AEI Solvix DC Plus Bias, 300 kHz	
	Rotary table	
	Control hardware	
	Control software	
	Other	

FOR DISCUSSION PURPOSES ONLY



FOR DISCUSSION PURPOSES ONLY

LAFAD-1000-C2

